

Inventor: Jerome M. Eldridge

Title: Perovskite-Type Material Forming Methods, Capacitor Dielectric Forming  
Methods, and Capacitor Constructions

Assignee: Micron Technology, Inc.

Docket No.: MI22-2395

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.


The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a divisional application of co-pending application Serial No. 10/208,154, filed July 29, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 14 Oct 2003

By: \_\_\_\_\_

  
James E. Lake  
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2395		Priority SERIAL NO. 10/208,154	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Jerome M. Eldridge			
				Priority FILING DATE July 29, 2002		Priority GROUP 2822	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,350,738	9/27/94	Hase et al			
	AB	5,350,738	09/19/94	Hase et al			
	AC	5,272,341	12/1993	Micheli et al			
	AD	5,142,437	08/1992	Kammerdiner et al			
	AE	6,461,931	10/2002	Eldridge			
	AF	6,025,257	02/2000	Jeon, Yoo Chan			
	AG	5,789,268	08/1998	Chivukula			
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes   No
	AJ						
	AK						
	AL						
	AM						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AN		John Baliga, "New Materials Enhance Memory Performance", Semiconductor International, November 1999, pgs. 1-8.				
	AO		"Advances in Ultrathin Oxides and Oxynitrides I", Materials Research Society Symposium Proceedings Series, Vol. 567, April 5, 1999, 2 pages.				
	AP		K.S. Tang, W.S. Lau, and G.S. Samudra, "Trends in Dram Dielectrics", IEEE Circuits & Devices, Vol. 13, No. 3, May 1997, pgs. 27-34				
	AQ		D.W. Hess, "Plasma-assisted oxidation, anodization, and nitridation of silicon", IBM Journal of Research & Development, Vol. 43, No. 1/2, Plasma processing, 22 pages.				
	AR		O. Kubaschewski, E. LL. Evans, "Metallurgical Thermochemistry", Pergamon Press, 1958, pgs. 226-227 and 336-337				
	AS		Ting, Chen, Liu, "Structural evolution and Optical properties of TiO <sub>2</sub> thin films prepared by thermal oxidation of sputtered Ti films", Journal of Applied Physics, Vol. 88, Number 9, 15 October 2000, pgs.4628-4633.				
	AT		O. Kubaschewski, B.E. Hopkins, "Oxidation of Metals and Alloys", Butterworths, London, Second Edition, 1962, pgs. 36-37 and 70-73.				
	AU		F.P. Fehlner, "Low-Temperature Oxidation", Monograph published by Electrochemical Society, Pennington, New Jersey, 1983, pgs.31-35.				
	AV		Richard A. Swalin, "Thermodynamics of Solids", Second Edition, Chapter 5, John Wiley & Sons, 1972, pgs.112-115.				
EXAMINER				DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1667	SERIAL NO. Filed Herewith	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Jerome M. Eldridge		
				FILING DATE Filed Herewith	GROUP Unknown	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	09/651,380	Eldridge (as filed and amended 3/28/02)			8/29/00
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
	AM					
	AN					
	AO					
	AP					
	AQ					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
	AR					
	AS					
	AT					
EXAMINER			DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>						